IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Mail Stop And endment

P.O. Box 1450

Alexandria, VA 22313-1450

Re: Inventor(s):

Michael R. Rice, Eric A. Englhardt, Vinay Shah, Martin R. Elliott, Robert B. Lowrance and Jeffrey C.

Hudgens

Title:

SYSTEMS AND METHODS FOR TRANSFERRING SMALL LOT SIZE SUBSTRATE CARRIERS

BETWEEN PROCESSING TOOLS

Serial No.:

10/764,620

Filed:

January 26, 2004

Examiner:

Kasenge, Charles R

Group Art Unit: 2125

Transmitted herewith is:

<u>X</u> PTO Form 1449;

X Information Disclosure Statement, and sixty-seven cited references (copy of fifty-nine references enclosed); and

X Return Postcard.

FEE CALCU	LATION		Constant		
· Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	N/A	- 20 =	-0-	X \$50.00	\$0.00
Independent Claims	N/A	- 3 =	-0-	X \$200.00	\$0.00
Basic Filing Fee	,			\$790.00	\$0.00
TOTAL FEES					PAID

The Commissioner is hereby authorized to charge \$0.00 to Deposit Account No. 04-1696.

<u>XX</u> The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. <u>04-1696</u>. A duplicate copy of this transmittal is enclosed.

XX Please address all future correspondence to:

Customer # 41161 Dugan & Dugan, PC 55 South Broadway Tarrytown, NY 10591

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

Express Mail Receipt No. <u>EV605115695US</u>

Date of Deposit: November 7, 200:

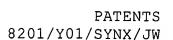
Signature

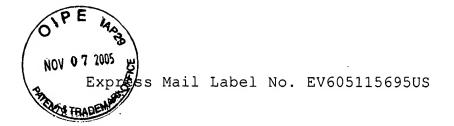
Respectfully submitted,

Brian M. Dugan

Registration No. 41,720

(914) 332-9081





IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Michael R. Rice, Eric A. Englhardt, Vinay

Shah, Martin R. Elliott, Robert B. Lowrance

and Jeffrey C. Hudgens

Serial No. : 10

10/764,620

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: January 26, 2004

For :

SYSTEMS AND METHODS FOR TRANSFERRING SMALL

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Group Art Unit:

2125

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Mail Stop Amendment

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In accordance with 37 C.F.R. §§ 1.56 and 1.97, applicants wish to call the attention of the Examiner to the following references:

- U.S. Patent No. 5,544,350, Hung et al.
- U.S. Patent No. 5,612,886, Yi-Cherng Weng
- U.S. Patent No. 5,818,716, Chin et al.
- U.S. Patent No. 5,825,650, Tza-Huei Wang

- U.S. Patent No. 5,971,585, Dangat et al.
- U.S. Patent No. 6,128,588, Guillermo Rudolfo Chacon
- U.S. Patent No. 6,196,001, Tannous et al.
- U.S. Patent No. 6,415,260, Yang et al.
- Foreign Art Reference No. JP 55091839 A (Japan)
- Foreign Art Reference No. JP 58028860 A (Japan)
- Foreign Art Reference No. JP 60049623 A (Japan)
- Foreign Art Reference No. JP 01181156 A (Japan)
- Foreign Art Reference No. JP 01257549 A (Japan)
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These references are also listed on the accompanying Information Disclosure Statement (Form PTO-1449).

Consideration of the foregoing in relation to this patent application is respectfully requested.

Respectfully Submitted,

Brian M. Dugan, Esq., Registration No. 41,720

Dugan & Dugan, PC
Attorneys for Applicants

(914)332-9081

Dated: November 7, 2005

Tarrytown, New York

U.S. Department of Commerce, Patent and Trademark Office Docket No.: 8201/YO	Serial No.: 10/764,620	

LIST C	F RELEV	ANT ART	CITED BY	APPLICANT

(Use several sheets if necessary)

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8201/Y01/SYNX/JW	10/764,620
Applicants:	
Michael R. Rice, et al	
Filing Date:	Group:
January 26, 2004	2125

Examiner		Document	Issue			·	Filing	Date If
Initial		Number	Date	Name	Class	Subclass	Appr	opriate
	US-1	5,544,350	08/06/96	Hung et al.				
	US-2	5,612,886	03/18/97	Yi-Cherng Weng				
	US-3	5,818,716	10/06/98	Chin et al.				
	US-4	5,825,650	10/20/98	Tza-Huei Wang				
	US-5	5,971,585	10/26/99	Dangat et al.				
	US-6	6,128,588	10/03/00	Guillermo Rudolfo Chacon	181 - 1			
	US-7	6,196,001	03/06/01	Tannous et al.				
	US-8	6,415,260	07/02/02	Yang et al.				
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	F-2	JP 58028860 A	02/19/83	Japan			Abstract	
	F-3	JP 60049623 A	03/18/85	Japan			Abstract	
	F-4	JP 01181156 A	07/19/89	Japan			Abstract	
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

Examiner

No. 3, Pg. 483-7.

Date Considered

U.S. Depar	rtment o	f Commerce, Pate	ent and Trade	emark Office	Docket No 8201/	o.: Y01/SYNX/JW		Serial No.: 10/764,620			
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	OT-5	Lou, S. et al., "U	sing simulati	on to test the rob	ustness of va	rious existing p	production cont	rol policies"	, 1991,		
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	OT-6	Berg, R. et al., "IEEE/SEMI Inter							, 1992,		
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	F-11	JP 09115817 A	05/02/97	Japai	n			Abstract			
	F-12	JP 10135096 A	05/22/98	Japai	n			Abstract			
	F-13	JP 11176717 A	07/02/99	Japai	n		14*1. <u></u>	Abstract			
	F-14	JP 11296208 A	10/29/99	Japai	n			Abstract			
	F-15	JP 01332464 A	11/30/01	Japan	n		·	Abstract			
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	OT-7	Naguib, H., "The 1992, IEEE/SEN							ration",		
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	F-16	JP 03007584 A	01/10/03	Jap	an			Abstract		
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	F-18	EP 1128246 A2	08/29/01	EP	0			Х		
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OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

- OT-10 Leonovich, G. A. et al., "Integrated cost and productivity learning in CMOS semiconductor manufacturing", Jan.-March 1995, IBM Journal of Research and Development, Vol. 39 No. 1-2, Pg. 201-13.
- OT-11 Leonovich, G., " An approach for optimizing WIP/cycle time/output in a semiconductor fabricator", 1994, Sixteenth IEEE/CPMT International Electronics Manufacturing Technology Symposium. 'Low-Cost Manufacturing Technologies for Tomorrow's Global Economy'. Proceedings 1994 IEMT Symposium, Vol. 1, Pg. 108-11.
- OT-12 Schomig, A. K. et al., "Performance modelling of pull manufacturing systems with batch servers", 1995, Proceedings 1995 INRIA/IEEE Symposium on Emerging Technologies and Factory Automation. ETFA'95, Vol. 3, Pg. 175-83.

Examiner

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LIST O		VANT ART CIT several sheets if		LICANT	Applicant Michael F	ts: R. Rice, et al					
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